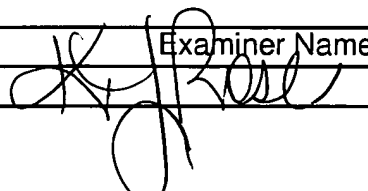


## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	METHOD AND STRUCTURE OF VERTICAL STRAINED SILICON DEVICES						
<p>Application Number : 10/605 227</p> <p>Confirmation Number:</p> <p>First Named Applicant: Kangguo Cheng</p> <p>Attorney Docket Number: FIS920030221US1</p> <p>Art Unit:</p> <p>Examiner:</p> <p>Search string: ( 6313486 or 6503833 or 6524935 or 5461243 or 5847419 or 6429061 or 5256550 ),pn</p>							
<b>US Patent Documents</b>							
<b>Note: Applicant is not required to submit a paper copy of cited US Patent Documents</b>							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
KL	1	6313486	2001-11-06	Kencke, et al.			
	2	6503833	2003-01-07	Ajmera, et al.			
	3	6524935	2003-02-25	Canaperi, et al.			
	4	5461243	1995-10-24	Ek, et al.			
	5	5847419	1998-12-08	Imai, et al.			
	6	6429061	2002-08-06	Rim			
KL	7	5256550	1993-10-26	Laderman, et al.			
<b>Signature</b>							
				Examiner Name			
				Date			
				5/20/04			